## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

I hereby certify that this correspondence is being electronically filed with the United States Patent and Trademark Office on July 16, 2007 at or before 11:59 p.m. Pacific Time under the Rules of 37 CFR 81.8

Melie a a

Applicant : Nam Hun Kim Confirmation No. 5813

Application No. : 10/593,857

Filed: September 22, 2006

Title : PLASMA CHAMBER HAVING PLASMA SOURCE COIL AND

METHOD FOR ETCHING THE WAFER USING THE SAME

Grp./Div. : 1763

Examiner : To be assigned

Docket No. : 58409/N305

SUBMISSION OF SMALL ENTITY DECLARATION

Commissioner for Patents P.O. Box 1450 Post Office Box 7068 Pasadena, CA 91109-7068 July 16, 2007

Alexandria, VA 22313-1450

## Commissioner:

Applicant hereby submits the executed Declaration Claiming Small Entity Status for a Small Business Concern for the above-identified patent application. Entry of this Declaration is requested.

Respectfully submitted,

CHRISTIE, PARKER & HALE, LLP

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By\_

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DBP/vdw Enclosure

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